

SEMICONDUCTOR SENSOR WITH PRESSURE DIFFERENCE
ADJUSTING MEANS

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ABSTRACT OF THE DISCLOSURE

10 In a semiconductor sensor having a membrane
structure, the destruction of the membrane caused by the
expansion or contraction of a fluid within a hollow part
formed under the membrane while the sensor is in use is
prevented. A semiconductor sensor 10 comprising a
15 substrate 30 and a membrane 20 formed on the top surface
thereof, in which the bottom of the substrate 30 and a
mounting surface 50 on which the sensor 10 is mounted are
bonded, has pressure difference adjusting means 22a to
22c for eliminating the difference in pressure of a fluid
20 between an inside and an outside of a hollow part 34
while the sensor is in use.